



TFW

In re Application of:

Docket No. 00862.022239

SHIGEYUKI UZAWA, ET AL.

Application No.: 09/864,309

Examiner: Ryan A. Jarrett

Filed: May 25, 2001

Group Art Unit: 2125

For: EXPOSURE APPARATUS, COATING/DEVELOPING SYSTEM, DEVICE MANUFACTURING SYSTEM, DEVICE MANUFACTURING METHOD, SEMICONDUCTOR MANUFACTURING FACTORY, AND EXPOSURE APPARATUS MAINTENANCE METHOD Date: July 26, 2004

COMMISSIONER FOR PATENTS
P.O. Box 1450
Alexandria, Virginia 22313-1450

Sir:

Transmitted herewith is a Preliminary Amendment in the above-identified application.

☒ No additional fee is required.

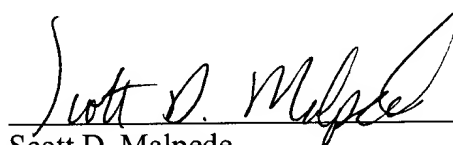
The fee has been calculated as shown below

| CLAIMS AS AMENDED | | | | | | |
|--|--|-------|--|-------------------------|----------------|-------------------|
| | (2) CLAIMS REMAINING AFTER AMENDMENT | | (4) HIGHEST NO. PREVIOUSLY PAID FOR | (5) PRESENT EXTRA | RATE | ADDITIONAL FEE |
| TOTAL CLAIMS | 15 | MINUS | 47 | = 0 | x \$9 \$18 | 0.00 |
| INDEP. CLAIMS | 1 | MINUS | 9 | = 0 | x \$43 \$86 | 0.00 |
| Fee for Multiple Dependent claims \$145°/\$290 | | | | | | 0.00 |
| TOTAL ADDITIONAL FEE FOR THIS AMENDMENT--- | | | | | | 0.00 |

☐ °Verified Statement claiming small entity status is enclosed, if not filed previously.

- ☐ A check in the amount of \$____ is enclosed.
- ☐ Charge \$____ to Deposit Account No. 06-1205. A duplicate copy of this sheet is enclosed.
- ☒ Any prior general authorization to charge an issue fee under 37 C.F.R. 1.18 to Deposit Account No. 06-1205 is hereby revoked. The Commissioner is hereby authorized to charge any additional fees under 37 C.F.R. 1.16 and 1.17 which may be required during the entire pendency of this application, or to credit any overpayment, to Deposit Account No. 06-1205. A duplicate copy of this paper is enclosed.
- ☐ A check in the amount of \$____ to cover the fee for a ____ month extension is enclosed.
- ☐ A check in the amount of \$____ to cover the Information Disclosure Statement fee is enclosed.
- ☒ Applicants' undersigned attorney may be reached in our Washington, D.C. office by telephone at (202) 530-1010. All correspondence should continue to be directed to our address given below.

Respectfully submitted,



Scott D. Malpede
Attorney for Applicants
Registration No. 32,533

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SDM:eyw

DC_MAIN 172844v1

00862.022239



PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

| | | |
|-------------------------------|---|---------------------------|
| In re Application of: |) | |
| | : | Examiner: Ryan A. Jarrett |
| SHIGEYUKI UZAWA, ET AL. |) | |
| | : | Group Art Unit: 2125 |
| Application No.: 09/864,309 |) | |
| | : | |
| Filed: May 25, 2001 |) | |
| | : | |
| For: EXPOSURE APPARATUS, |) | July 26, 2004 |
| COATING/DEVELOPING SYSTEM | : | |
| DEVICE MANUFACTURING SYSTEM, |) | |
| DEVICE MANUFACTURING METHOD, | : | |
| SEMICONDUCTOR MANUFACTURING |) | |
| FACTORY, AND EXPOSURE | : | |
| APPARATUS MAINTENANCE METHOD) | | |

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PRELIMINARY AMENDMENT AND
STATEMENT OF SUBSTANCE OF INTERVIEW

Sir:

Prior to examination on the merits, please amend the above-identified
application in the following manner: